

Energy Harvesting from Ambient Vibrations

Frédéric Giraud

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Energy Harvesting from Ambient Vibrations

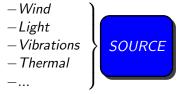
Frédéric Giraud

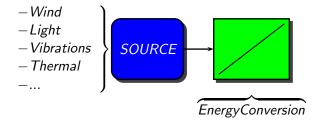
L2EP - University Lille1

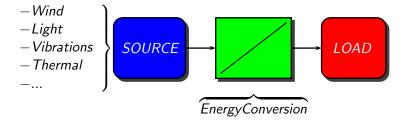
November 27, 2012

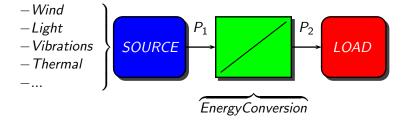
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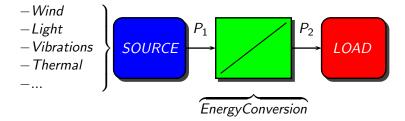






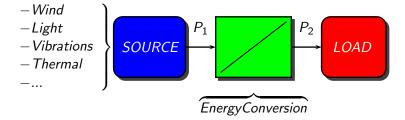


We extract energy from an ambient and free source:



We talk about **Energy Harvesting** or also **energy scavenging** when the converted power is small, typically less than 1W.

We extract energy from an ambient and free source:



We talk about **Energy Harvesting** or also **energy scavenging** when the converted power is small, typically less than 1W. $\eta = \frac{P_2}{P_1} = 1 - \frac{P_1 - P_2}{P_1} \longrightarrow \text{Losses in the energy converter should be as small as possible.}$

Objectives: Sensors Network



www.perpetuum.com

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www.perpetuum.com





Gutiérriez, A Heterogeneous Wireless Identification Network for the Localization of Animals Based on Stochastic Movements

Objectives: Sensors Network



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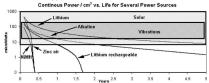




Gutiérriez, A Heterogeneous Wireless Identification Network for the Localization of Animals Based on Stochastic Movements



http://www.rfwirelesssensors.com, 2012



Roundy et Al.:A study of low level vibrations as a power source for wireless sensor nodes.

Objectives: Power, just where you need it



http://enocean.com

- Wireless
- Reduce Cost, and is reconfigurable
- Better Waste Cycle (Information from Enocean)

Objectives: Power, just where you need it



http://enocean.com

- Wireless
- Reduce Cost, and is reconfigurable
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Innowattech's systems produces power with vehicles



http://www.innowattech.com

Objectives: Power, just where you need it





http://enocean.com

- Wireless
- Reduce Cost, and is reconfigurable
- Better Waste Cycle (Information from Enocean)



http://www.innowattech.com



The economist - April 28th 2007



Objectives: Marketing Purpose

Experience: Same Remote controller energized by human power, but with different packaging.

"No need for Batteries"

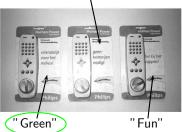
"No need for Batteries"

"One of the particular of the part

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54% of people Will choose the first one because it is eco-friendly. (Jansen, Human power empirically explored)

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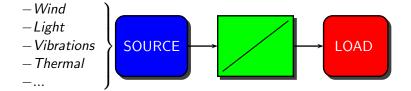
54% of people Will choose the first one because it is eco-friendly.
(Jansen, Human power empirically explored)

Several projects are born from this fact: **Metis** Produces energy from dancers' movements.

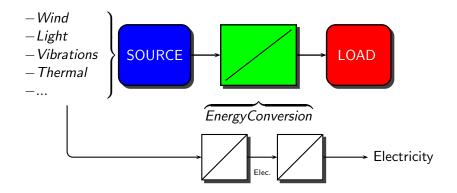


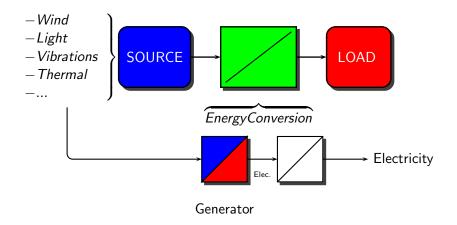
In Toulouse, the system **VIHA** proposes Smart Tiles to energies street lights.

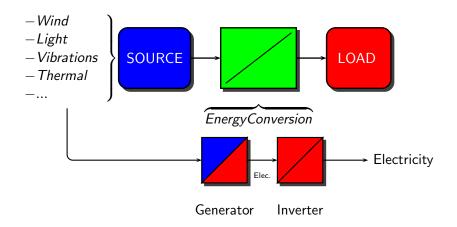




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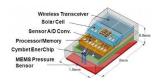




What is Energy Harvesting?
Generator Technologies
Summary

Solar Harvesters:

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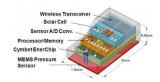


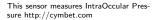


This sensor measures IntraOccular Pressure http://cymbet.com

Handbag to recharge electronic devices http://www.neubers.de

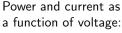
Solar Harvesters:

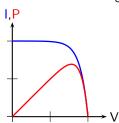


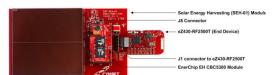




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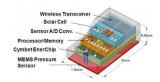






Solar Energy Harvester Evaluation Kit http://ti.com

Solar Harvesters:

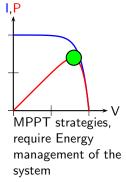




This sensor measures IntraOccular Pressure http://cymbet.com

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Power and current as a function of voltage:



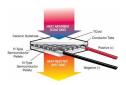
Solar Energy Harvesting (SEH-91) Modula
JB Connector

- c2439-RF2500T (End Device)

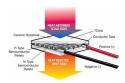
J1 connector to c2439-RF2500T

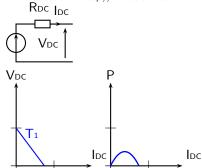
EnerChip EH CBC5300 Module

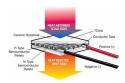
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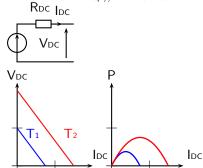


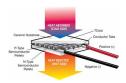


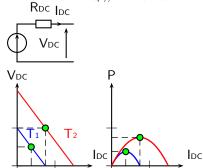


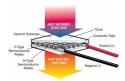


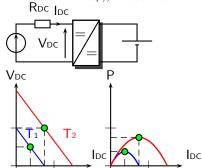


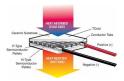




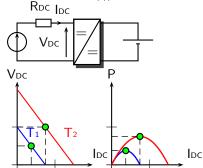


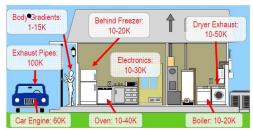






A Peltier module from http://www.tellurex.com



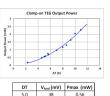


Temperature Gradient (residential). Lindsay Miller, http://uc-ciee.org

Clamp-on Drain Harvester



Master E2D2



1.16

2.05

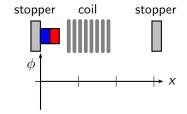
plumbing application from http://www.nextreme.com

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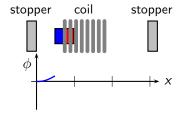
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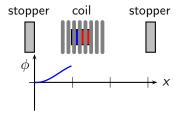
Magnetic

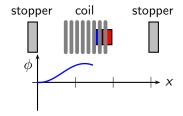


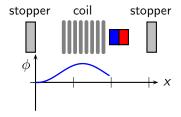
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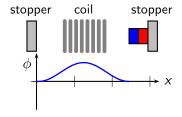


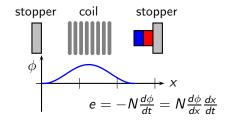
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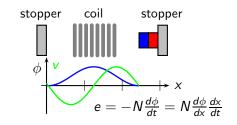




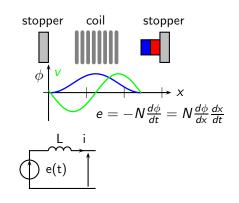




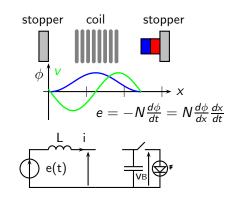




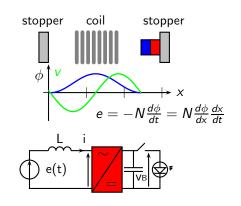




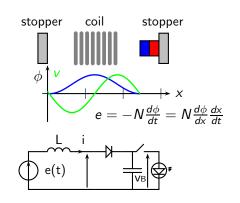




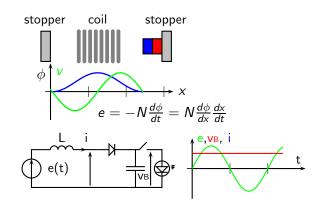




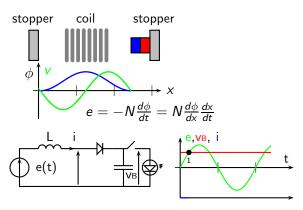






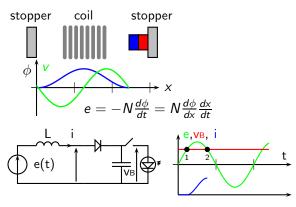






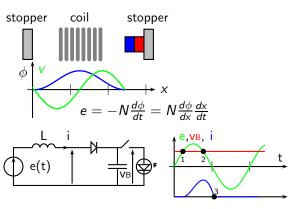


1) Diode turns ON



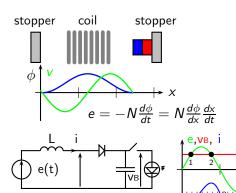


- 1) Diode turns ON
- 2) $\frac{di}{dt} = 0$ because $e v_B = 0$



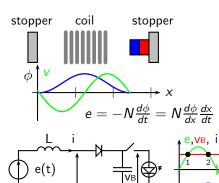


- 1) Diode turns ON
- 2) $\frac{di}{dt} = 0$ because $e v_B = 0$
- 3) i = 0, diode turns OFF



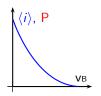


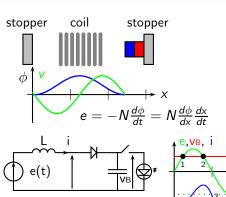
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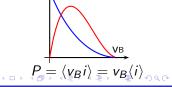


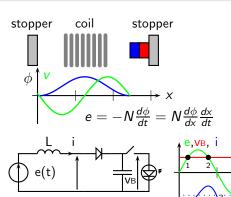




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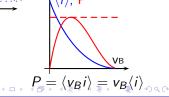


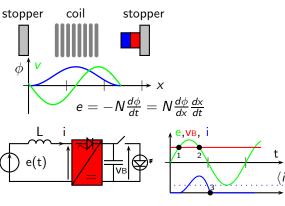




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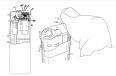






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An electronic lighter, http://freepatentsonline.com



Piezoelectric crystals

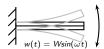


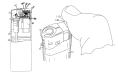
An electronic lighter, http://freepatentsonline.com



Piezoelectric crystals

Cantilever beam



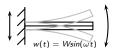


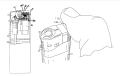
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Piezoelectric crystals

Cantilever beam



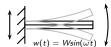


An electronic lighter, http://freepatentsonline.com



Piezoelectric crystals

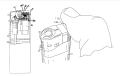
Cantilever beam



Equivalent electrical circuit



 i_m is a current proportional to the deformation speed

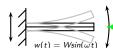


An electronic lighter, http://freepatentsonline.com



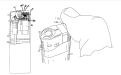
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Cantilever beam



Equivalent electrical circuit



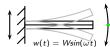


An electronic lighter, http://freepatentsonline.com



Piezoelectric crystals

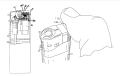
Cantilever beam



Equivalent electrical circuit



Companson Magni Ticzo	
Magnetic	Piezo.
Voltage source	Current
	source
Inductive	capacitive
Large Stroke	Small
	Stroke
Remote action	

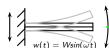


An electronic lighter, http://freepatentsonline.com



Piezoelectric crystals

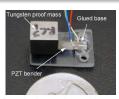
Cantilever beam



Equivalent electrical circuit



Companicon magni i iczo	
Magnetic	Piezo.
Voltage source	Current
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Roundy, A piezoelectric vibration based generator for wireless electronics (2004)

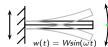


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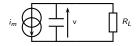


Piezoelectric crystals

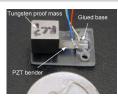
Cantilever beam



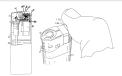
Equivalent electrical circuit



Companison Magni 1 1020	
Magnetic	Piezo.
Voltage source	Current
	source
Inductive	capacitive
Large Stroke	Small
	Stroke
Remote action	



Roundy, A piezoelectric vibration based generator for wireless electronics (2004)

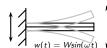


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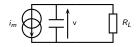


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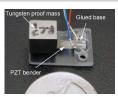
Cantilever beam



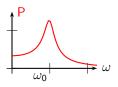
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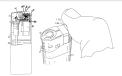


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Magnetic	Piezo.
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Inductive	capacitive
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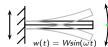


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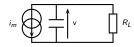


Piezoelectric crystals

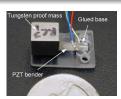
Cantilever beam



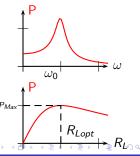
Equivalent electrical circuit

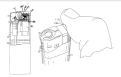


Companison Magn. 1 1020	
Magnetic	Piezo.
Voltage source	Current
	source
Inductive	capacitive
Large Stroke	Small
	Stroke
Remote action	



Roundy, A piezoelectric vibration based generator for wireless electronics (2004)



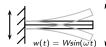


An electronic lighter, http://freepatentsonline.com

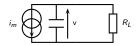


Piezoelectric crystals

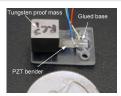
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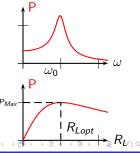
Energy Management Equivalent electrical circuit

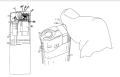


Companison Magn. 1 1620	
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Voltage source	Current
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Inductive	capacitive
Large Stroke	Small
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Remote action	



Roundy, A piezoelectric vibration based generator for wireless electronics (2004)



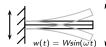


An electronic lighter, http://freepatentsonline.com

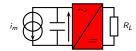


Piezoelectric crystals

Cantilever beam

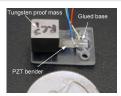


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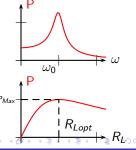


i_m is a current proportional to the deformation speed Comparison Magn. Piezo

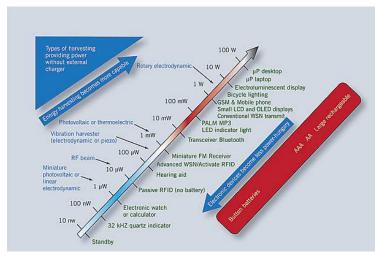
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Roundy, A piezoelectric vibration based generator for wireless electronics (2004)



There is no "one fit all" solution

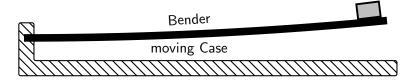


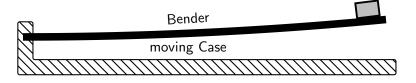
Each solution may be efficient in a certain range of Power.

Meanwhile, shrinking Chips consumption come at a time when energy harvesting becomes efficient and practical (source: IDtechex.com)

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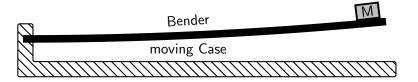
- Introduction
 - What is Energy Harvesting?
 - Generator Technologies
 - Summary
- 2 Modelling of a piezoelectric energy harvester
 - Presentation of the system
 - EMR of the system
 - \bullet Power Extraction on a load resistor R_L from harmonic oscillation
- An Example of inverter
 - Introduction
 - SSHI: Synchronized Switch Harvesting on Inductor



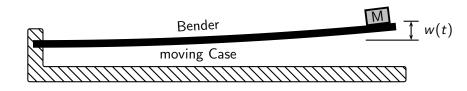


 The bender is attached to a vibrating and rigid case,



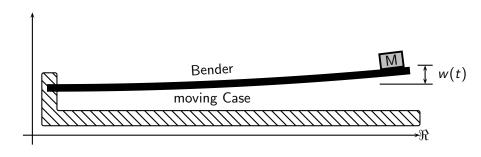


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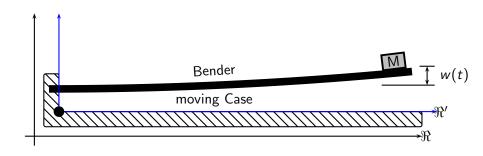
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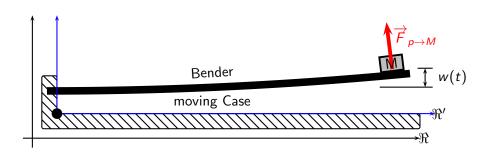
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- We define R a fixed reference frame.





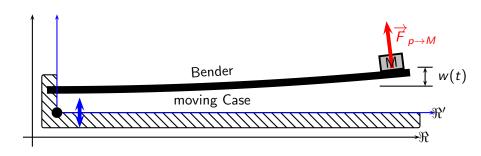
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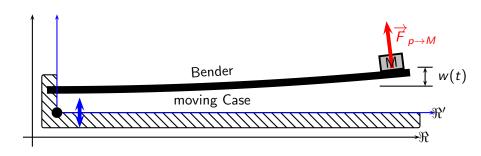
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 $\overrightarrow{F}_{p \to m}$ is the force of the Bender onto the mass M.



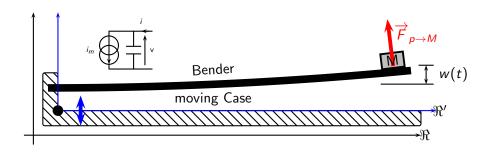
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- Actuator electrical convention



• Dynamic of the mass *M*:

- M the mass
- f, the force onto M
- A, vibration's amplitude
- ω , vibration's pulsation
- f_{acc} is the inertial force
- i current of the device (actuator convention)
- im motional current
 - f_D inside piezo force
- N Piezoelectric force factor (depends on geometry)
- f_p Piezo internal force
- f_s Material internal elastic force
- K_s equivalent stiffness (depends on geometry)
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$$M\frac{d^2}{dt^2}(w(t) + A\sin(\omega t)) = F_{p\to M} = f$$

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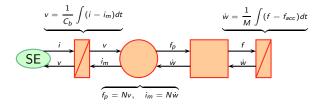
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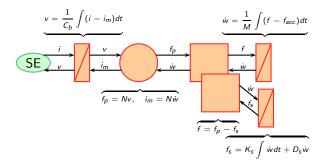
$$SE v$$

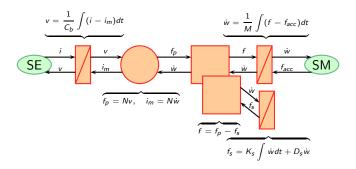
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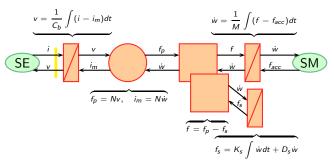
$$i_m$$

$$f_p = Nv, \quad i_m = N\dot{w}$$

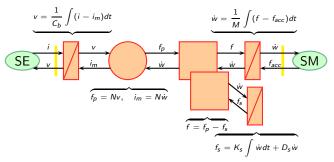




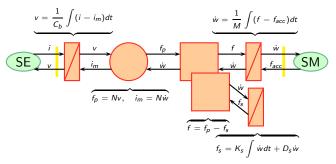




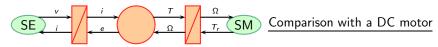
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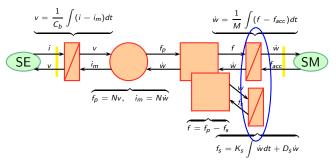


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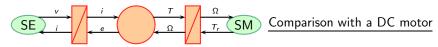


Things are not so differerent.





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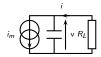
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- since oscillations are harmonic, we will write: $\underline{x} = \underline{X}e^{j\omega t}$
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- $v = -R_L i$

Asumption

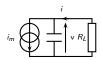
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And
$$R_L \ll \frac{1}{C_b \omega}$$
, yields $v \simeq -R_L i_m$



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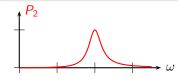
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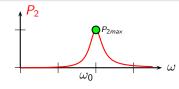
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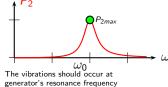
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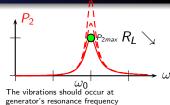
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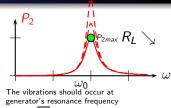
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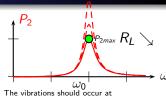
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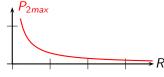
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The vibrations should occur at generator's resonance frequency

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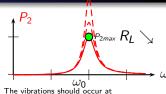
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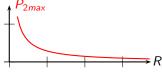
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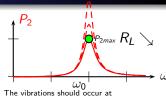
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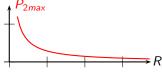
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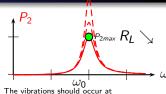
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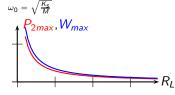
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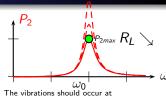
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generator's resonance frequency

$$\omega_0 = \sqrt{\frac{\kappa_s}{M}}$$

$$P_{2max}, W_{max}$$

We can harvest as much power as we want, at the expense of large displacement of the bender's tip

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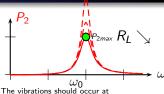
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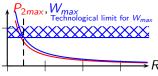
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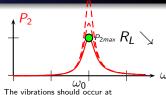
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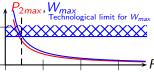
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$$\begin{array}{l} \bullet \ \ P_{2Max} = \frac{(MA\omega^2)^2}{2N^2R_L}, \ W_{max} = \frac{MA\omega}{N^2R_L}, \\ v_{max} = \frac{MA\omega^2}{N} \end{array}$$



The vibrations should occur at generator's resonance frequency

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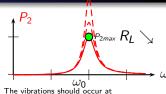
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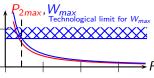
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$$P_{1Max} = \frac{1}{2} f_{acc} \omega W_{Max} = \frac{(MA\omega^2)^2}{N^2 R_I} = P_{2Max}$$



generator's resonance frequency

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Master E2D2

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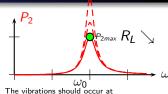
$$\bullet |i_m| = N|\dot{w}| = \frac{\omega \cdot N \cdot |f_{acc}|}{\sqrt{(K_s - M\omega^2)^2 + (N^2 R_L \omega)^2}}$$

•
$$P_2 = -\frac{1}{2} \frac{N^2 R_L \omega^2 |f_{acc}|^2}{(K_s - M \omega^2)^2 + (N^2 R_L \omega)^2}$$

$$P_{2Max} = \frac{(MA\omega^2)^2}{2N^2R_L}, \ W_{max} = \frac{MA\omega}{N^2R_L},$$

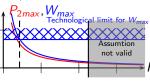
$$v_{max} = \frac{MA\omega^2}{N}$$

•
$$P_{1Max} = \frac{1}{2} f_{acc} \omega W_{Max} = \frac{(MA\omega^2)^2}{N^2 R_I} = P_{2Max}$$



generator's resonance frequency

$$\omega_0 = \sqrt{\frac{K_S}{M}}$$



We can harvest as much power as we want, at the expense of large displacement of the bender's tip

Master E2D2

$$\bullet \ \underline{f} = N\underline{v} - K_s\underline{w} - D_s\underline{\dot{w}}$$

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•
$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

$$\bullet \ \underline{f} = N\underline{v} - K_s\underline{w} - D_s\underline{\dot{w}}$$

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$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

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$$P_1 = -\frac{1}{2} \frac{(D_s + R_L N^2)\omega^2 |\underline{f}_{acc}|^2}{(K_s - M\omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

$$\bullet \ \underline{f} = N\underline{v} - K_s\underline{w} - D_s\underline{\dot{w}}$$

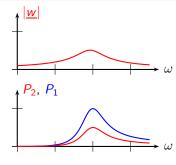
$$\bullet \ \underline{W} = \frac{\underline{f}_{acc}}{(K_s - M\omega^2) + j\omega(D_s + N^2R_L)}$$

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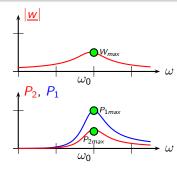
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$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

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$$\bullet \ \underline{f} = N\underline{v} - K_s\underline{w} - D_s\underline{\dot{w}}$$

$$\bullet \ \underline{W} = \frac{\underline{f}_{acc}}{(K_s - M\omega^2) + j\omega(D_s + N^2R_L)}$$

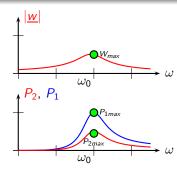
•
$$P_2 = -\frac{1}{2}R_L|i_m|^2$$

•
$$P_2 = -\frac{1}{2} \frac{R_L N^2 \omega^2 |\underline{f}_{acc}|^2}{(K_s - M\omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

•
$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

•
$$P_1 = -\frac{1}{2} \frac{(D_s + R_L N^2) \omega^2 |\underline{f}_{acc}|^2}{(K_s - M \omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

 ω_0 should still be the vibration's pulsation.



$$\bullet \ \underline{f} = N\underline{v} - K_s\underline{w} - D_s\underline{\dot{w}}$$

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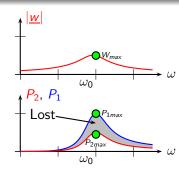
•
$$P_2 = -\frac{1}{2}R_L|i_m|^2$$

•
$$P_2 = -\frac{1}{2} \frac{R_L N^2 \omega^2 |\underline{f}_{acc}|^2}{(K_s - M\omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

•
$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

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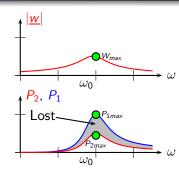
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•
$$P_2 = -\frac{1}{2} \frac{R_L N^2 \omega^2 |\underline{f}_{acc}|^2}{(K_s - M\omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

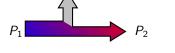
•
$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

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$$P_1 = -\frac{1}{2} \frac{(D_s + R_L N^2) \omega^2 |\underline{f}_{acc}|^2}{(K_s - M \omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

 ω_0 should still be the vibration's pulsation.



Generator's Power Losses



$$\bullet \ \underline{f} = N\underline{v} - K_s\underline{w} - D_s\underline{\dot{w}}$$

$$\bullet \ \underline{W} = \frac{\underline{f}_{acc}}{(K_s - M\omega^2) + j\omega(D_s + N^2R_L)}$$

•
$$P_2 = -\frac{1}{2}R_L|i_m|^2$$

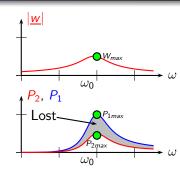
•
$$P_2 = -\frac{1}{2} \frac{R_L N^2 \omega^2 |\underline{f}_{acc}|^2}{(K_s - M\omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

•
$$P_1 = -\frac{1}{2}\Re(\underline{f}_{acc}.\underline{\dot{w}}^*)$$

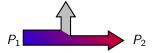
•
$$P_1 = -\frac{1}{2} \frac{(D_s + R_L N^2) \omega^2 |\underline{f}_{acc}|^2}{(K_s - M \omega^2)^2 + \omega^2 (D_s + N^2 R_L)^2}$$

 ω_0 should still be the vibration's pulsation.

$$\begin{array}{l} \bullet \quad W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L) \omega_0}, \; P_{1max} = \frac{1}{2} \frac{|\underline{f}_{acc}|^2}{D_s + N^2 R_L}, \\ P_{2max} = \frac{1}{2} \frac{N^2 R_L |\underline{f}_{acc}^2|}{(D_s + N^2 R_I)^2} \\ \end{array}$$





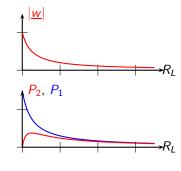


•
$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
, $P_{1max} = \frac{1}{2} \frac{|f_{acc}|^2}{D_s + N^2 R_L}$

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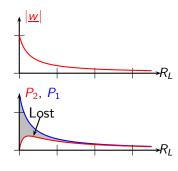
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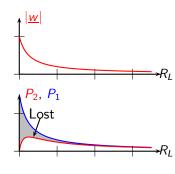
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•
$$R_{Lopt} = \frac{D_s}{N^2}$$
,

$$P_{2opt} = \frac{|\underline{f}_{acc}|^2}{8D_s}$$

•
$$P_{1opt} = \frac{|f_{acc}|^2}{4D_s} = 2.P_{2opt}$$



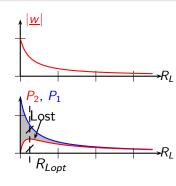
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$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
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•
$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
, $P_{1max} = \frac{1}{2} \frac{|f_{acc}|^2}{D_s + N^2 R_L}$

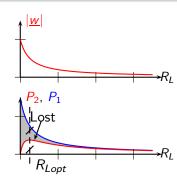
$$P_{2max} = \frac{1}{2} \frac{N^2 R_L |\underline{f}_{acc}|^2}{(D_s + N^2 R_L)^2}$$

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•
$$|\underline{v_{max}}| = NR_L \omega_0 |\underline{w}| = \frac{NR_L |f_{acc}|}{(D_s + N^2 R_L)}$$



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$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
, $P_{1max} = \frac{1}{2} \frac{|f_{acc}|^2}{D_s + N^2 R_L}$

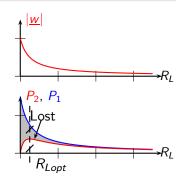
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$$P_{2max} = \frac{1}{2} \frac{N^2 R_L |\underline{f}_{acc}|^2}{(D_s + N^2 R_L)^2}$$

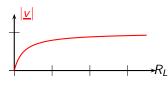
•
$$R_{Lopt} = \frac{D_s}{N^2}$$
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$$|\underline{v_{max}}| = NR_L \omega_0 |\underline{w}| = \frac{NR_L |f_{acc}|}{(D_s + N^2 R_L)}$$





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$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
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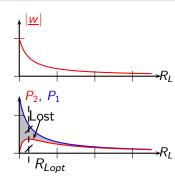
When $R_L \searrow$, $P_1 \nearrow$, which is good, but the losses increase as well: it exists an optimal value of R_L which optimizes P_2 for a given vibration amplitude. It can be shown:

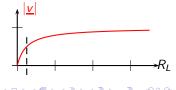
•
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$$P_{2opt} = \frac{|\underline{f}_{acc}|^2}{8D_s}$$

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$$P_{1opt} = \frac{|f_{acc}|^2}{4D_s} = 2.P_{2opt}$$

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$$|\underline{v_{max}}| = NR_L \omega_0 |\underline{w}| = \frac{NR_L |f_{acc}|}{(D_s + N^2 R_L)}$$





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$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
, $P_{1max} = \frac{1}{2} \frac{|f_{acc}|^2}{D_s + N^2 R_L}$

•
$$P_{2max} = \frac{1}{2} \frac{N^2 R_L |\underline{f}_{acc}|^2}{(D_s + N^2 R_L)^2}$$

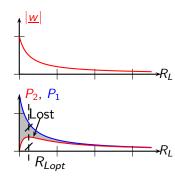
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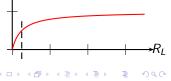
•
$$R_{Lopt} = \frac{D_s}{N^2}$$
,

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•
$$P_{1opt} = \frac{|f_{acc}|^2}{4D_s} = 2.P_{2opt}$$

voltage is not so high.





•
$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0}$$
, $P_{1max} = \frac{1}{2} \frac{|f_{acc}|^2}{D_s + N^2 R_L}$

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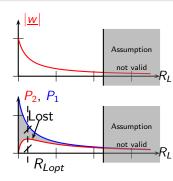
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$$R_{Lopt} = \frac{D_s}{N^2}$$
,

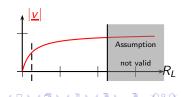
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$$|\underline{v_{max}}| = NR_L \omega_0 |\underline{w}| = \frac{NR_L |f_{acc}|}{(D_s + N^2 R_L)}$$

voltage is not so high.





Master E2D2

Example

Device's properties

$$N = 0.012 N/V$$
, $K_s = 6300 N/m$, $C_b = 300 nF$, $D_s = 0.17 Ns/m$, $M = 1g$

Calculate for A = 0.1mm

- the best working frequency,
- the harvested P_2 power in the best case.
- the power of the source P_1 in such best case.
- the optimal resistor R_I ,
- the deflection amplitude of the bender,
- the voltage for this working point.

Validation

Is $v = -R_L i_m$ a valid assumption?

• The best working frequency is given by

$$f_0 = \frac{1}{2\pi} \sqrt{\frac{K_s}{M}} = \frac{1}{2\pi} \sqrt{\frac{6300}{1.10^{-3}}} = \underline{400Hz}$$

• The best working frequency is given by

$$f_0 = \frac{1}{2\pi} \sqrt{\frac{K_s}{M}} = \frac{1}{2\pi} \sqrt{\frac{6300}{1.10^{-3}}} = \underline{400Hz}$$

• For the best case, P_2 is given by

$$P_2 = \frac{|f_{acc}|^2}{8D_s} = \frac{(1.10^{-3}.1.10^{-4}.(2\pi.400)^2)^2}{8.0,17} = \underline{464mW}$$

• The best working frequency is given by

$$f_0 = \frac{1}{2\pi} \sqrt{\frac{K_s}{M}} = \frac{1}{2\pi} \sqrt{\frac{6300}{1.10^{-3}}} = \underline{400Hz}$$

• For the best case, P_2 is given by $P_2 = \frac{|\underline{f}_{acc}|^2}{8D_s} = \frac{(1.10^{-3}.1.10^{-4}.(2\pi.400)^2)^2}{8.0.17} = \frac{464 mW}{8.0.17}$

• For the best case $P_1 = 2.P_2 = 928 \, mW$

• The best working frequency is given by

$$f_0 = \frac{1}{2\pi} \sqrt{\frac{K_s}{M}} = \frac{1}{2\pi} \sqrt{\frac{6300}{1.10^{-3}}} = \underline{400Hz}$$

- For the best case, P_2 is given by $P_2 = \frac{|\underline{f}_{acc}|^2}{8D_s} = \frac{(1.10^{-3}.1.10^{-4}.(2\pi.400)^2)^2}{8.0.17} = \underline{464mW}$
- For the best case $P_1 = 2.P_2 = 928 \, mW$
- The optimal resistor R_{Lopt} is given by $R_{Lopt} = \frac{D_s}{N^2} = \frac{0.17}{0.012^2} = \frac{1180\Omega}{10.012}$

• The best working frequency is given by

$$f_0 = \frac{1}{2\pi} \sqrt{\frac{K_s}{M}} = \frac{1}{2\pi} \sqrt{\frac{6300}{1.10^{-3}}} = \underline{400Hz}$$

- For the best case, P_2 is given by $P_2 = \frac{|\underline{f}_{acc}|^2}{200} = \frac{(1.10^{-3} \cdot 1.10^{-4} \cdot (2\pi \cdot 400)^2)^2}{20.17} = 464 \, \text{mW}$
- For the best case $P_1 = 2.P_2 = 928 \, mW$
- The optimal resistor R_{Lopt} is given by $R_{Lopt} = \frac{D_s}{N^2} = \frac{0.17}{0.012^2} = \frac{1180\Omega}{1000}$
- The deflection W_{max} is given by

$$W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0} = \frac{(1.10^{-3}.1.10^{-4}.(2\pi.400)^2)}{2.0,17.2\pi.400} = \underline{738\mu m!}$$

The best working frequency is given by

$$f_0 = \frac{1}{2\pi} \sqrt{\frac{K_s}{M}} = \frac{1}{2\pi} \sqrt{\frac{6300}{1.10^{-3}}} = \underline{400Hz}$$

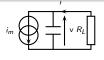
- For the best case, P_2 is given by $P_2 = \frac{|f_{acc}|^2}{8D_s} = \frac{(1.10^{-3}.1.10^{-4}.(2\pi.400)^2)^2}{8.0.17} = \underline{464mW}$
- For the best case $P_1 = 2.P_2 = 928 mW$
- The optimal resistor R_{Lopt} is given by $R_{Lopt} = \frac{D_s}{N^2} = \frac{0.17}{0.012^2} = \frac{1180\Omega}{1000}$
- The deflection W_{max} is given by $W_{max} = \frac{|f_{acc}|}{(D_s + N^2 R_L)\omega_0} = \frac{(1.10^{-3}.1.10^{-4}.(2\pi.400)^2)}{2.0,17.2\pi.400} = \underline{738\mu m!}$
- The voltage is then given by $v_{max} = NR_L\omega_0|\underline{w}| = 0,012.1180.2\pi.400.738.10^{-6} = \underline{26V}$



The best working frequency is given by

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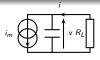
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- $Z_{Cb} = \frac{1}{C_h \omega} = \frac{1}{2\pi \ 400 \ 300 \ 10^{-9}} = \underline{1990\Omega} \approx R_L$, \longrightarrow Calculations are NOT valid!





We can show:

$$\underline{v} = -\frac{R_L}{1+j\omega R_L C_b} \underline{i}_m = -j\omega N R_L \frac{1-j\omega R_L C_b}{1+(R_L C_b \omega)^2} \underline{w}_m$$
 and we write:
$$\underline{v} = -j\omega N r_{Leq} \underline{w} - N k_{eq} \underline{w}$$



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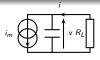
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$$+ \omega$$



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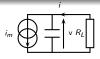
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$$\omega_0 \downarrow 1$$

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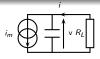
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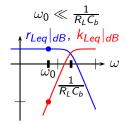
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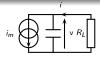
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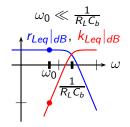
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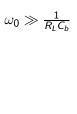
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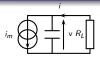
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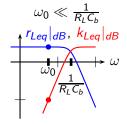




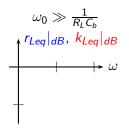
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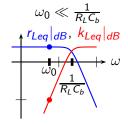




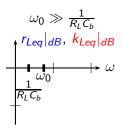
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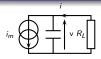
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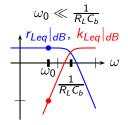




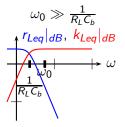
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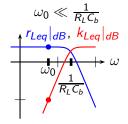




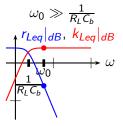
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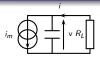
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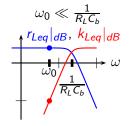
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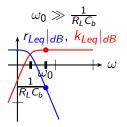


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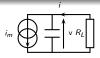
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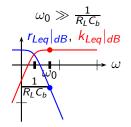
$$\omega_0 \ll \frac{1}{R_L C_b}$$

$$\uparrow^{r_{Leq}} |_{dB}, \underset{k_{Leq}}{\downarrow^{k_{Leq}}} |_{dB}$$

$$\downarrow^{\omega_0} \downarrow^{1}$$

$$\downarrow^{R_L C_b}$$

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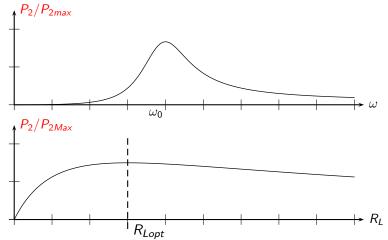
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Frédéric Giraud Master E2D2 November 27, 2012 23 / 40

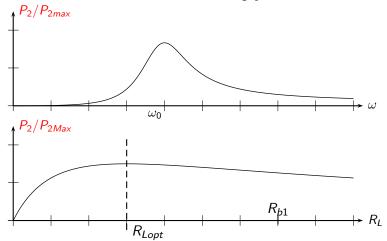
Rule of the Thumb

Let
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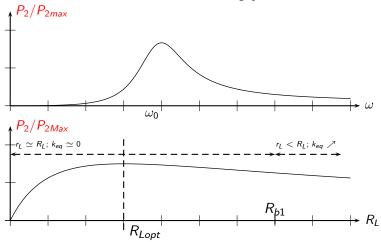
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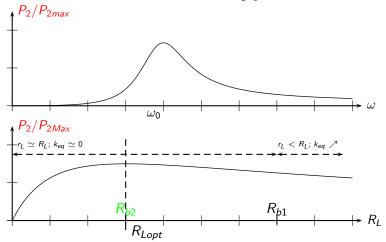


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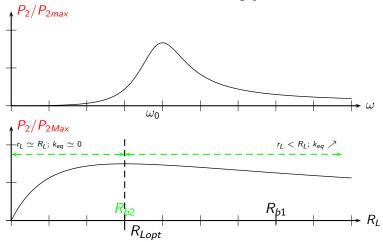
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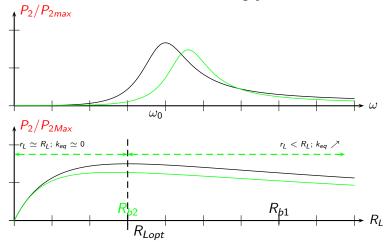
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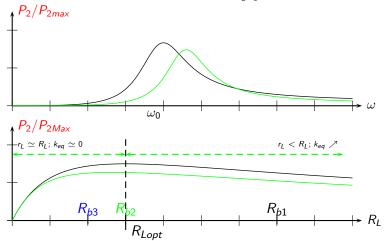
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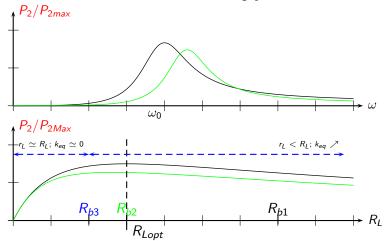
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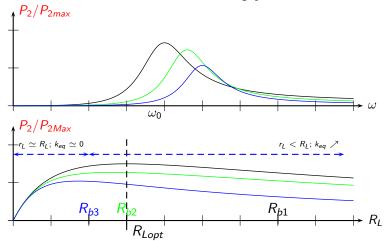
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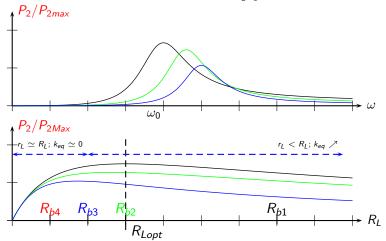
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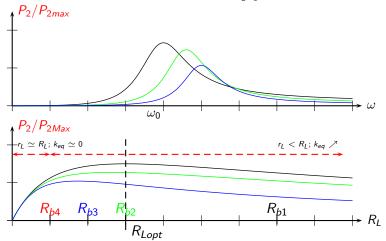
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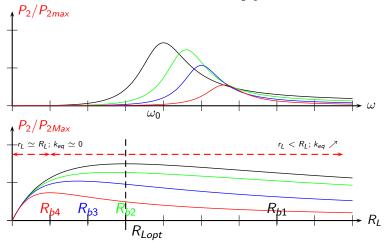
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Partial Conclusion

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A resistor can recover the power optimally. But the study was not valid for high R_L . What happens for $R_L \gg R_b$?

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If $R_{opt} > R_b$

The power is not well extracted because $P_2 < P_{2max}$. This happens for high damped mechanisms.

A simple resistor cannot recover the power optimally (and this is due to C_h).

resonance is shifted

•
$$r_{Leq} = \frac{R_L}{1 + (R_L C_b \omega)^2} \simeq \frac{R_L}{(R_L C_b \omega)^2}$$

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$$k_{eq} = R_L \frac{\omega^2 R_L C_b}{1 + (R_L C_b \omega)^2} \simeq \frac{1}{C_b}$$

$$((K_s + N^2 k_e q) - M\omega^2) + j\omega(D_s + N^2 r_{Leq})\underline{w} = \underline{f}_{acc}$$
 leads to:

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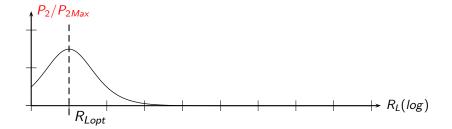
Another optimal resistor

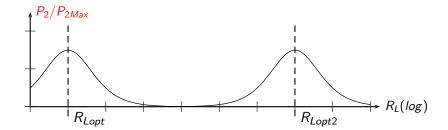
The optimal power is harvested is $N^2 r_{Leq} = D_s$, leading to:

$$\frac{N^{2}R_{L}}{(R_{L}C_{b}\omega'_{0})^{2}} = \frac{N^{2}}{R_{L}C_{b}^{2}\frac{K_{s}+\frac{N^{2}}{C_{b}}}{M}} = D_{s}$$

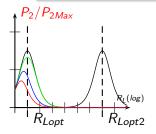
$$R_{Lopt2} = \frac{N^{2}}{D_{s}}\frac{1}{C_{b}^{2}\frac{K_{s}}{M}(1+\frac{N^{2}}{K_{s}C_{L}})} = \frac{R_{b}^{2}}{R_{Lopt}}\frac{1}{1+\frac{N^{2}}{K_{s}C_{L}}}$$



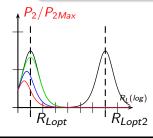


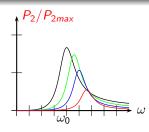


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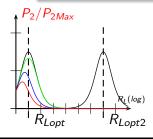


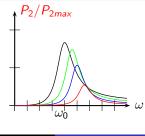
- For the realistic case, there is one or two resistive loads which allow to extract the maximum of power,
- There exist an optimal frequency which may vary if R_L is very high,

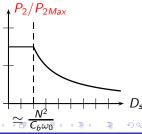




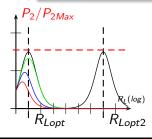
- For the realistic case, there is one or two resistive loads which allow to extract the maximum of power,
- There exist an optimal frequency which may vary if R_L is very high,
- For highly damped structure, a simple resistor is not optimal.

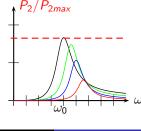






- For the realistic case, there is one or two resistive loads which allow to extract the maximum of power,
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- For highly damped structure, a simple resistor is not optimal.
- \rightarrow we always want to harvest the maximum of power!





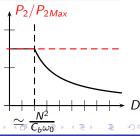
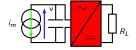
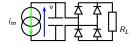
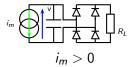


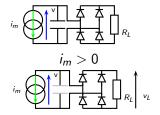
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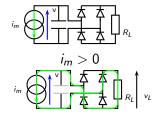
- Introduction
 - What is Energy Harvesting ?
 - Generator Technologies
 - Summary
- Modelling of a piezoelectric energy harvester
 - Presentation of the system
 - EMR of the system
 - \bullet Power Extraction on a load resistor R_L from harmonic oscillation
- 3 An Example of inverter
 - Introduction
 - SSHI: Synchronized Switch Harvesting on Inductor

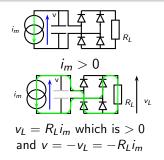


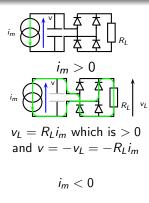


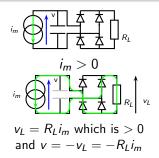


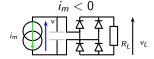


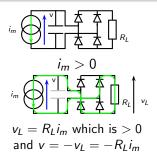


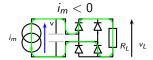


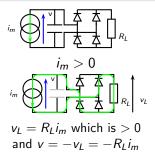


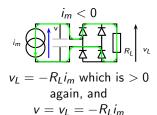


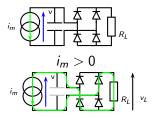




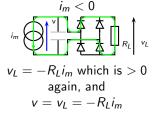


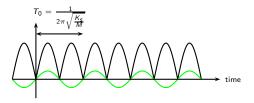


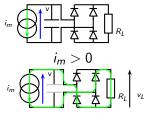




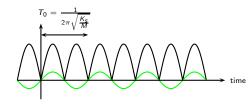
$$v_L = R_L i_m$$
 which is > 0
and $v = -v_L = -R_L i_m$



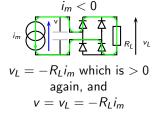


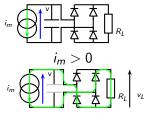


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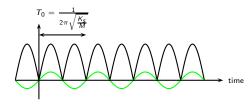


The current is rectified, but we still have $v = -R_L i_m$: Power harvesting depends on R_L

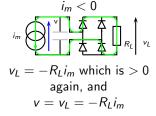


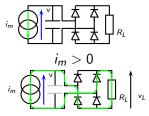


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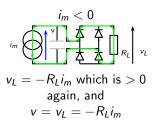


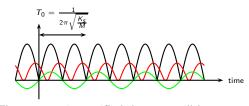
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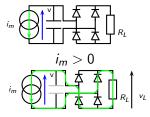


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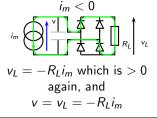


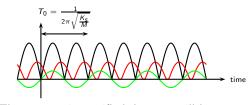


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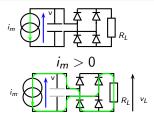


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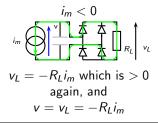


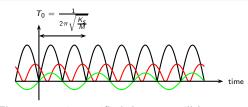


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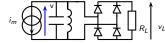


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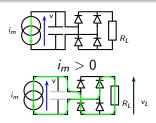




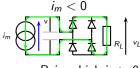
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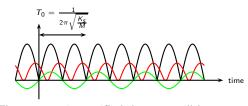
Introduction



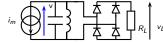
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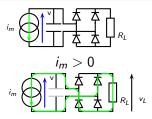


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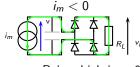


This is a bad solution because it works only for ω_0 (what if the frequency shifts?), and the Inductor is large (because ω_0 usually is small)

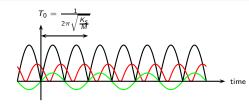
Introduction



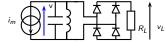
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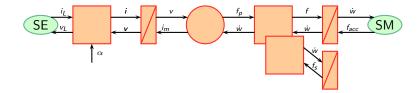
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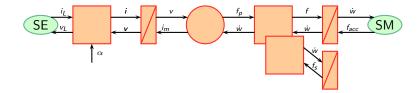


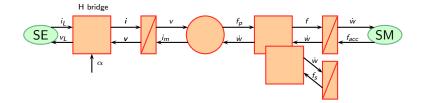
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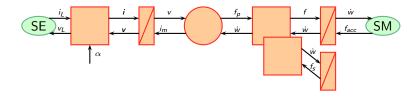


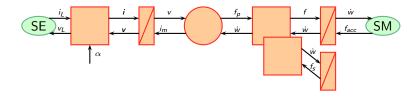
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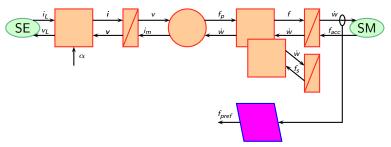


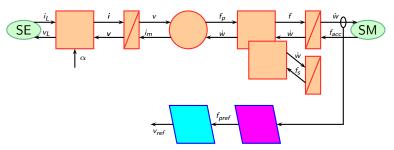


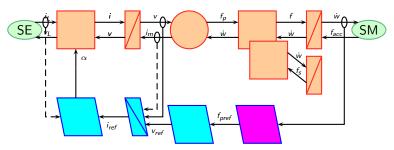




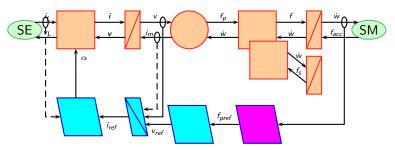








Strategy: $v = -R_{opt}i_m$ leads to $\frac{f_p}{N} = -\frac{D_s}{N^2}N\dot{w}$ or, $f_p = -D_s\dot{w}$. This shows that v should be controlled.

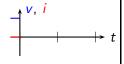


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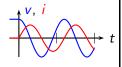






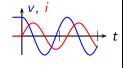






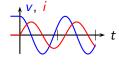
LC oscillations





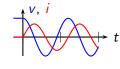
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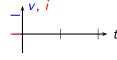


LC oscillations



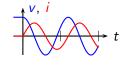




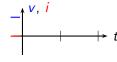


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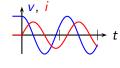




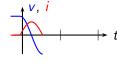


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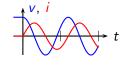




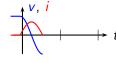


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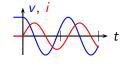




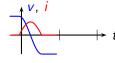


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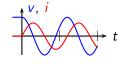




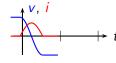


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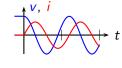




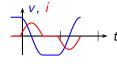


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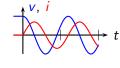




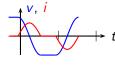


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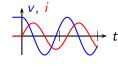




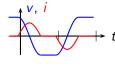


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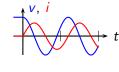






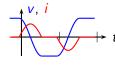
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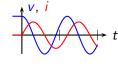
Switched inductor





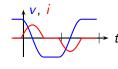
LC oscillations

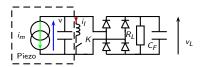




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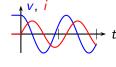






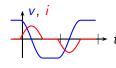
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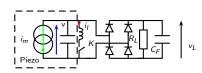


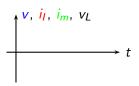


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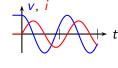






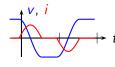
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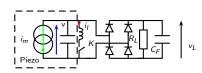


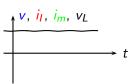


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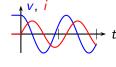






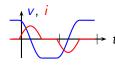
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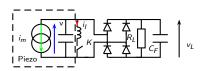


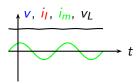


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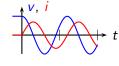






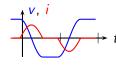
LC oscillations

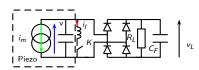


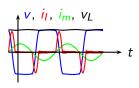


Switched inductor



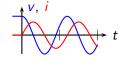






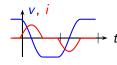
LC oscillations



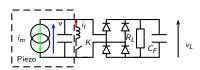


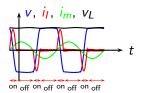
Switched inductor





SSHI



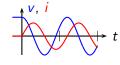


Switching is synchronized on \dot{w} , or

$$i_m = N\dot{w}$$
.

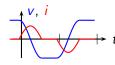
LC oscillations



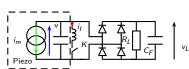


Switched inductor



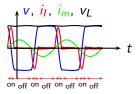


SSHI



Operating point: calculate v_I from i_m

 1^{st} Harmonic assumption: $P=\frac{1}{2}\frac{V_L^2}{R_I}\simeq \frac{1}{2}\frac{4V_L l_m}{\pi},~V_L=\frac{4}{\pi}R_L l_m$

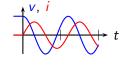


Switching is synchronized on \dot{w} , or

 $i_m = N\dot{w}$.

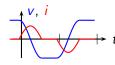
LC oscillations



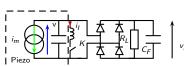


Switched inductor





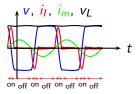
SSHI



Operating point: calculate v_l from i_m

 $1^{\rm st} \ {\rm Harmonic \ assumption:} \ P = \frac{1}{2} \frac{V_L^2}{R_I} \, \simeq \, \frac{1}{2} \, \frac{4 V_L I_m}{\pi}, \ V_L = \frac{4}{\pi} R_L I_m$

SSHI controls v and synchronises it, but doesn't impose $f_p = -D_S \dot{w}$.



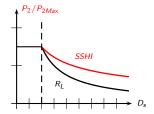
Switching is synchronized on \dot{w} , or

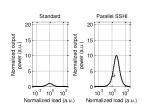
$$i_m = N\dot{w}$$
.

Conclusion

Performances

• SSHI can extract energy more efficiently than a resistor when damping is important,

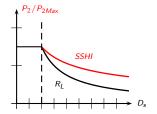


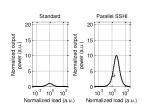


Conclusion

Performances

- SSHI can extract energy more efficiently than a resistor when damping is important,
- But Power extraction still depends on the load,

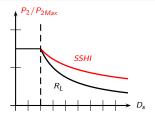


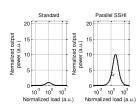


Conclusion

Performances

- SSHI can extract energy more efficiently than a resistor when damping is important,
- But Power extraction still depends on the load,
- Needs to measure bender's deflection w(t).





General conclusion

In this presentation, applications of Energy Harvesting were shown. The modelling of a piezoelectric generator has shown that the power source needs an adaptation:

- in frequency,
- in load.

to maximize the harvested poer.

The key energy management rules were presented through the analysis of the EMR of the system. A typical power electronic circuit was also presented, but the bibliography shows a lot of example.

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End of the presentation

Questions?